

S1 (arrow marks): $R_s > 99\%$ @ 195 - 201 nm + $R_p < 1\%$ @ 261 - 267 nm + $R_s < 10\%$ @ 390 - 400 nm + $R_s < 10\%$ @ 780 - 800 nm, AOI=45 deg
 GDD R_s @ 195 - 201 nm ± 100 fs², AOI=45 deg

S2: $R_p < 0.8\%$ @ 261 - 267 nm + $R_s < 3\%$ @ 390 - 400 nm + $R_s < 5\%$ @ 780 - 800 nm, AOI=45 deg

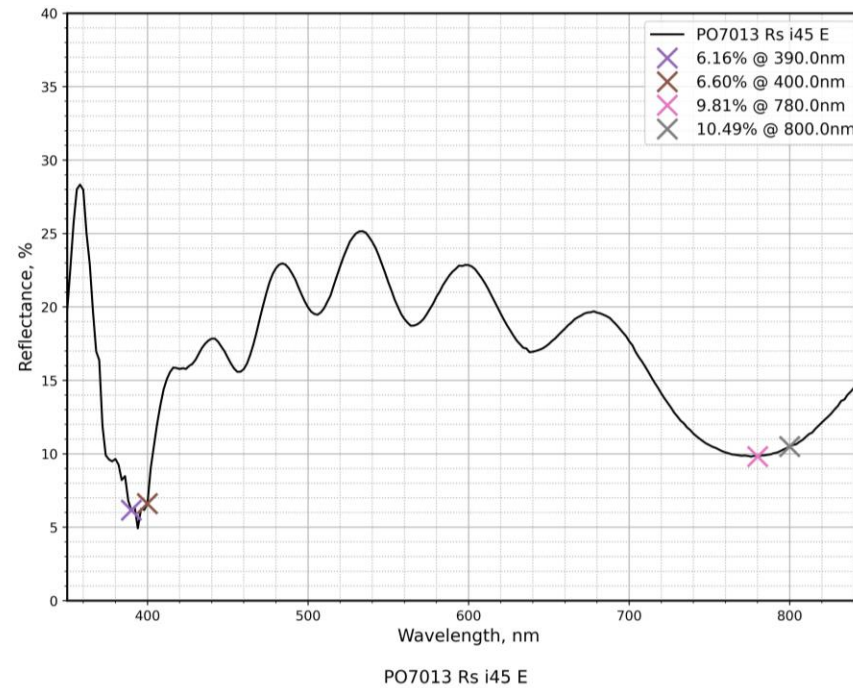


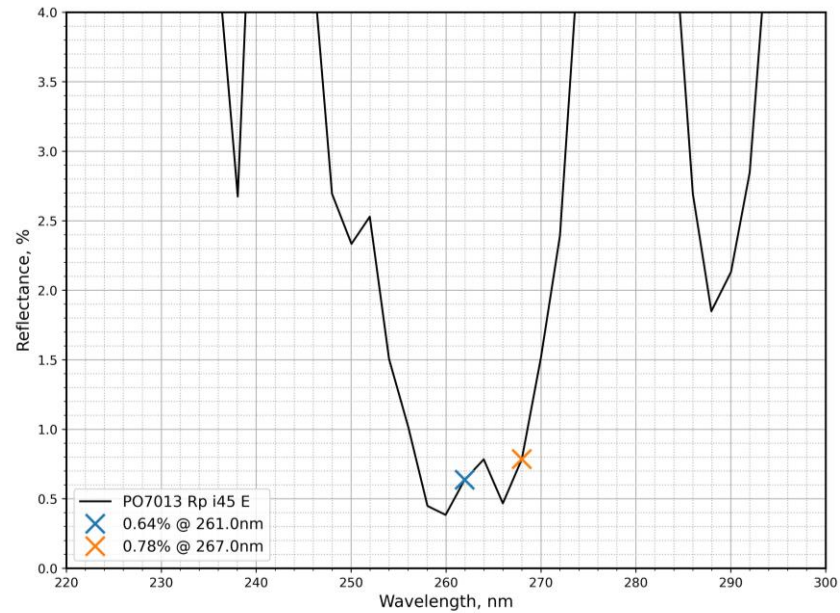
Fig. 1.

SIDE MEASURED: S1+S2 (good component)

COMMENTS: Margin of measurement error: $\pm 0.25\%$

S1 (arrow marks): $R_s > 99\%$ @ 195 - 201 nm + $R_p < 1\%$ @ 261 - 267 nm + $R_s < 10\%$ @ 390 - 400 nm + $R_s < 10\%$ @ 780 - 800 nm, AOI=45 deg
 GDD R_s @ 195 - 201 nm ± 100 fs², AOI=45 deg

S2: $R_p < 0.8\%$ @ 261 - 267 nm + $R_s < 3\%$ @ 390 - 400 nm + $R_s < 5\%$ @ 780 - 800 nm, AOI=45 deg



PO7013 Rp i45 E

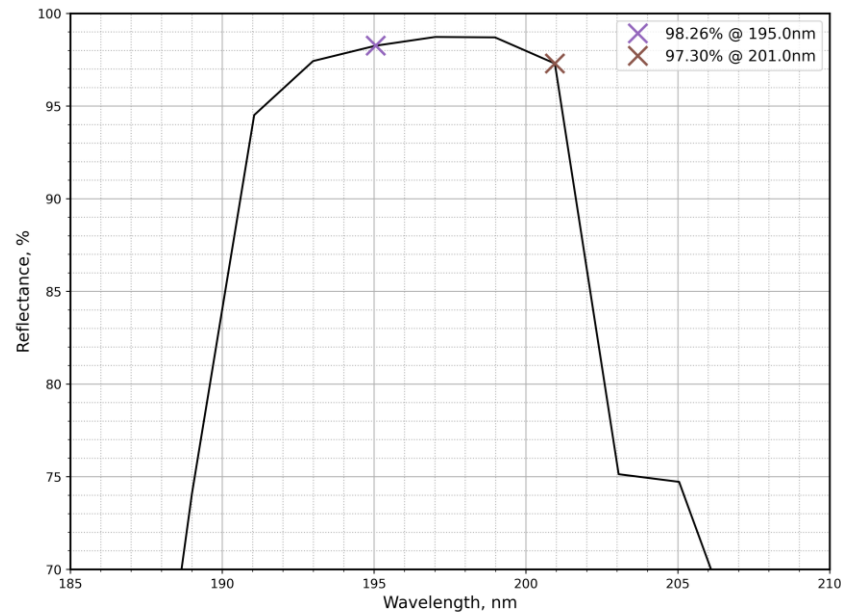
Fig. 2.

SIDE MEASURED: S1+S2 (good component)

COMMENTS: Margin of measurement error: $\pm 0.25\%$

S1 (arrow marks): $R_s > 99\%$ @ 195 - 201 nm + $R_p < 1\%$ @ 261 - 267 nm + $R_s < 10\%$ @ 390 - 400 nm + $R_s < 10\%$ @ 780 - 800 nm, AOI=45 deg
 GDD R_s @ 195 - 201 nm ± 100 fs², AOI=45 deg

S2: $R_p < 0.8\%$ @ 261 - 267 nm + $R_s < 3\%$ @ 390 - 400 nm + $R_s < 5\%$ @ 780 - 800 nm, AOI=45 deg



PO7013 Ra i45 185-220 nm E

Fig. 3.

SIDE MEASURED: S1+S2 (good component)

COMMENTS: Margin of measurement error: $\pm 0.25\%$; R_s can't be measured directly because of spectrophotometer limitations. S-pol reflection theoretically will be higher by $\sim 1-1.5\%$.